Ultra high purity transducer For explosion-protected areas, Ex nA ic Models WU-20, WU-25 and WU-26

WIKA data sheet PE 87.07









Applications

- Gas panels for OEM tools
- Semiconductor, flat panel display and photovoltaic industry
- Special and bulk-gas supply

Special features

- High-accuracy pressure measurement 0.15 % RSS
- Excellent long-term stability
- Signal noise shielding and cancellation
- Active temperature compensation
- ATEX and IECEx zone 2 approval
 FM class I div. 2 groups A, B, C & D



Abb. left: WU-20, single end Abb. centre: WU-25, flow through

Abb. right: WU-26, modular surface mount

Description

Reliable

The WU-2x series combines state-of-the-art digital transducer concepts with analogue-like output signals, in order to provide the safest and most accurate pressure measurements necessary for today's market requirements.

Pressure measurement, based on a true vacuum reference, and electronic measures for interference shielding and signal noise cancellation ensure high-accuracy pressure measurement and excellent long-term stability.

Active temperature compensation reduces the impact of changing temperatures on the transducer, allowing safe operations even in applications with high fluctuations in temperature, e.g. Joule-Thomson effect in the case of gas expansion.

WU-25 (flow through) and WU-26 (surface mount) transducers are specifically designed to sustain torsion-applied stresses often incurred during installation. The special design of the thin-film sensor eliminates the risk of

sensor failure due to loads at the process connection or welded joints.

Versatile

The WU-2x transducer can be readily installed in indoor or outdoor systems as well as in non-flammable or potentially flammable areas. The hermetically sealed design of the WU-2x prevents the ingress of humidity.

Approvals for non-flammable and potentially flammable environments ensure a high level of product safety. Instruments for temperature class T6 meet the high requirements for low, spontaneous ignition temperature media (phosphine (PH3) and silane (SiH4)).

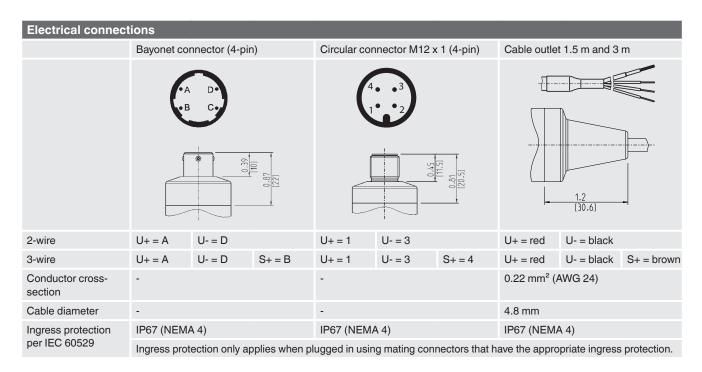
Compact

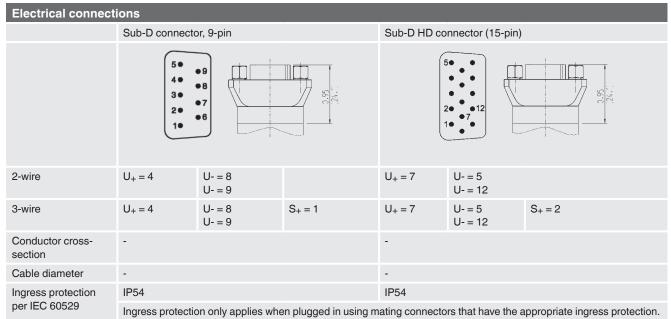
With its small footprint the WU-2x is the most compact UHP transducer in the market. Thus it is optimally suited for installation in applications with limited mounting space, and even in existing plants it can be easily retrofitted.

Part of your business

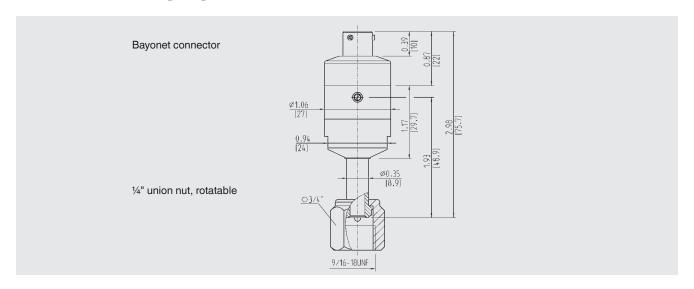
Model WU-20, WU-25											
	IV	lodel WU	l -2 6								
30	60	100	160	250	350	500	1,000	1,500	2,000	3,000	5,000
2	4	7	11	17	25	36	70	100	145	225	360
120	120	210	320	500	750	1,100	2,100	3,000	4,200	6,600	10,000
1,800	1,800	2,200	2,600	4,800	6,200	7,400	8,000	10,500	10,500	10,500	10,50
Furthe	r measur	ing range	s on requ	ıest							
Thin-film sensor											
Process connection: 316L stainless steel, according to SEMI F20 (option: 316L VIM/VAR) Thin-film sensor: 2.4711 / UNS R30003											
304 SS											
< 1 x 10 ⁻⁹ mbar l/sec (atm STD cc/sec) per SEMI F1											
Electropolished, typical Ra ≤ 0.13 μm (RA 5); max. Ra ≤ 0.18 μm (RA 7) per SEMI F19											
WU-20 < 1.5 cm ³ , WU-25 < 1 cm ³ , WU-26 < 1 cm ³											
Speciality gases, vapours, liquids											
DC 10 30 V with output signal DC 0 5 V / 4 20 mA DC 14 30 V with output signal DC 0 10 V											
4 20 mA, 2-wire, $R_A \le (U+-10 \text{ V}) / 0.02 \text{ A}$ DC 0 5 V, 3-wire, $R_A > 5 \text{ k}\Omega$ DC 0 10 V, 3-wire, $R_A > 10 \text{ k}\Omega$											
1 W											
-3.5 +3.5 % of span (via potentiometer), current output -2 +3.5 % of span (via potentiometer), voltage output											
≤ 300 ms											
DC 500 V											
\leq 0.15 % of span (\leq 0.4 % of span with measuring ranges \leq 2 bar) RSS (root sum squares) \leq 0.3 % of span ¹⁾ (\leq 0.6 % of span ¹⁾ with measuring ranges \leq 2 bar) per IEC 61298-2											
≤ 0.1 % of span (≤ 0.15 % of span for measuring ranges ≤ 2 bar) (BFSL) per IEC 61298-2											
≤ 0.14 % of span											
≤ 0.12 % of span											
≤ 0.25 % of span (typ.), at reference conditions (≤ 0.4 % of span with measuring ranges ≤ 2 bar)											
non-E	x		T4			T5			T6		
-20 +80 °C, -4 +176 °F (actively compensated)											
≤ 0.1 % of span/10 K											
Double packaging per SEMI E49.6											
500 g (1.5 ms) per IEC 60068-2-27											
U+ vs.	`	,									
	2 120 1,800 Further Thin-fi Proces Thin-fi 304 Si <1 x 1 Electrr WU-20 Special DC 10 DC 14 4 20 DC 0 DC 0 1 W -3.52 + ≤ 300 DC 50 ≤ 0.15 ≤ 0.3 ° ≤ 0.14 ≤ 0.25 non-E -204 +² -4020 ≤ 0.15 Clean Double 500 g 0.35 m S+ vs.	30 60 2 4 120 120 1,800 1,800 Further measur Thin-film senso 304 SS <1 x 10-9 mbar Electropolished WU-20 < 1.5 cr Speciality gase DC 10 30 V v DC 14 30 V v 4 20 mA, 2-w DC 0 5 V, 3-w DC 0 10 V, 3-1 W -3.5 +3.5 % of -2 +3.5 % of ≤ 300 ms DC 500 V ≤ 0.15 % of spar ≤ 0.14 % of spar ≤ 0.12 % of spar ≤ 0.12 % of spar ≤ 0.12 % of spar constant 100 °C -4 +212 °F -20 +85 °C -4 +100 °C -4 +212 °F -20 +85 °C -4 +212 °F -20 +80 °C, - ≤ 0.15 % of spar ≤ 0.15 % of spar constant 100 °C -4 +212 °F -20 +80 °C, - ≤ 0.1 % of spar ≤ 0.15 % of spar constant 100 °C -4 +212 °F -20 +80 °C, - ≤ 0.1 % of spar ≤ 0.15 % of spar	30 60 100 2 4 7 120 120 210 1,800 1,800 2,200 Further measuring range Thin-film sensor Process connection: 316 Thin-film sensor: 2.4711 304 SS <1 x 10-9 mbar l/sec (atm Electropolished, typical F WU-20 < 1.5 cm³, WU-25 Speciality gases, vapours DC 10 30 V with outpu DC 14 30 V with outpu DC 14 30 V with outpu 4 20 mA, 2-wire, R _A ≤ DC 0 5 V, 3-wire, R _A > DC 0 10 V, 3-wire, R _A > 1 W -3.5 +3.5 % of span (via ≤ 300 ms DC 500 V ≤ 0.15 % of span (≤ 0.4 % ≤ 0.3 % of span ¹) (≤ 0.6 % ≤ 0.1 % of span ≤ 0.12 % of span ≤ 0.12 % of span ≤ 0.25 % of span (typ.), a non-Ex -20 +100 °C -4 +212 °F -20 +85 °C -4 +185 °F -40 +100 °C -40 +212 °F -20 +80 °C, -4 +176 S 0.1 % of span/10 K Clean room class 5 per ls Double packaging per St 500 g (1.5 ms) per IEC 60 0.35 mm (10 58 Hz) / 5 S+ vs. U- (short time)	2 4 7 11 120 120 210 320 1,800 1,800 2,200 2,600 Further measuring ranges on requiremental regions of the sensor Process connection: 316L stainlest Thin-film sensor: 2.4711 / UNS R3 304 SS <1 x 10 ⁻⁹ mbar l/sec (atm STD cc. Electropolished, typical Ra ≤ 0.13 WU-20 < 1.5 cm³, WU-25 < 1 cm³ Speciality gases, vapours, liquids DC 10 30 V with output signal EDC 14 30 V with output signal EDC 10 5 V, 3-wire, $R_A > 5 k\Omega$ DC 0 10 V, 3-wire, $R_A > 10 k\Omega$ 1 W -3.5 +3.5 % of span (via potention signal explanation of span (via potention signal explanation signal explana	Model WU-26 30 60 100 160 250 2 4 7 11 17 120 120 210 320 500 1,800 1,800 2,200 2,600 4,800 Further measuring ranges on request Thin-film sensor Process connection: 316L stainless steel, a Thin-film sensor: 2.4711 / UNS R30003 304 SS < 1 x 10 ⁻⁹ mbar l/sec (atm STD cc/sec) per Electropolished, typical Ra ≤ 0.13 μm (RA WU-20 < 1.5 cm³, WU-25 < 1 cm³, WU-26 · Speciality gases, vapours, liquids DC 10 30 V with output signal DC 0 5 V DC 14 30 V with output signal DC 0 10 4 20 mA, 2-wire, R _A ≤ (U+ − 10 V) / 0.02 · DC 0 5 V, 3-wire, R _A > 5 kΩ DC 0 10 V, 3-wire, R _A > 10 kΩ 1 W -3.5 +3.5 % of span (via potentiometer), volume of span (span span span span span span span span	Model WU-26 30 60 100 160 250 350 2 4 7 11 17 25 120 120 210 320 500 750 1,800 1,800 2,200 2,600 4,800 6,200 Further measuring ranges on request Thin-film sensor Process connection: 316L stainless steel, according Thin-film sensor: 2.4711 / UNS R30003 304 SS <1 x 10-9 mbar l/sec (atm STD cc/sec) per SEMI F1 Electropolished, typical Ra ≤ 0.13 μm (RA 5); max. I WU-20 < 1.5 cm³, WU-25 < 1 cm³, WU-26 < 1 cm³ Speciality gases, vapours, liquids DC 10 30 V with output signal DC 0 5 V / 4 20 DC 14 30 V with output signal DC 0 10 V 4 20 mA, 2-wire, R _A ≤ (U+ − 10 V) / 0.02 A DC 0 10 V, 3-wire, R _A > 10 kΩ DC 0 10 V, 3-wire, R _A > 10 kΩ 1 W -3.5 +3.5 % of span (via potentiometer), current o -2 +3.5 % of span (via potentiometer), voltage out ≤ 300 ms DC 500 V ≤ 0.15 % of span (≤ 0.4 % of span with measuring rafe 0.14 % of span ≤ 0.1 % of span (≤ 0.15 % of span for measuring rafe 0.14 % of span ≤ 0.12 % of span ≤ 0.14 % of span ≤ 0.15 % of span (span (span span span span span span span span	Model WU-26 30 60 100 160 250 350 500 2 4 7 11 17 25 36 120 120 210 320 500 750 1,100 1,800 1,800 2,200 2,600 4,800 6,200 7,400 Further measuring ranges on request Thin-film sensor Process connection: 316L stainless steel, according to SEMI Thin-film sensor: Process connection: 316L stainless steel, according to SEMI Thin-film sensor: Process connection: 316L stainless steel, according to SEMI Thin-film sensor: Process connection: 316L stainless steel, according to SEMI Thin-film sensor: Process connection: 316L stainless steel, according to SEMI Thin-film sensor: Process connection: 316L stainless steel, according to SEMI Thin-film sensor: Process connection: 316L stainless steel, according to SEMI Thin-film sensor: Process connection: 316L stainless steel, according to SEMI Thin-film sensor: 88.01 8003 88c 18 <t< td=""><td>Model WU-26 30 60 100 160 250 350 500 1,000 2 4 7 11 17 25 36 70 120 120 210 320 500 750 1,100 2,100 1,800 1,800 2,200 2,600 4,800 6,200 7,400 8,000 Further measuring ranges on request Thin-film sensor Process connection: 316L stainless steel, according to SEMI F20 (opt Thin-film sensor: 2.4711 / UNS R30003 304 SS < 1 x 10° mbar l/sec (atm STD cc/sec) per SEMI F1</td> Electropolished, typical Ra ≤ 0.13 µm (RA 5); max. Ra ≤ 0.18 µm (RA WU-26 < 1 cm³</t<>	Model WU-26 30 60 100 160 250 350 500 1,000 2 4 7 11 17 25 36 70 120 120 210 320 500 750 1,100 2,100 1,800 1,800 2,200 2,600 4,800 6,200 7,400 8,000 Further measuring ranges on request Thin-film sensor Process connection: 316L stainless steel, according to SEMI F20 (opt Thin-film sensor: 2.4711 / UNS R30003 304 SS < 1 x 10° mbar l/sec (atm STD cc/sec) per SEMI F1	Model WU-26 30 60 100 160 250 350 500 1,000 1,500 2 4 7 11 17 25 36 70 100 120 120 210 320 500 750 1,100 2,100 3,000 1,800 1,800 2,200 2,600 4,800 6,200 7,400 8,000 10,500 Further measuring ranges on request Thin-film sensor Process connection: 316L stainless steel, according to SEMI F20 (option: 316L Thin-film sensor Process connection: 316L stainless steel, according to SEMI F20 (option: 316L Thin-film sensor Process connection: 316L stainless steel, according to SEMI F20 (option: 316L Thin-film sensor Process connection: 316L stainless steel, according to SEMI F20 (option: 316L Thin-film sensor Process connection: 316L stainless steel, according to SEMI F20 (option: 316L Thin-film sensor: 316L Th	Model WU-26 30 60 100 160 250 350 500 1.000 1.500 2.000 120 120 210 320 500 750 1.100 2.100 3.000 4.200 1,800 1,800 2,200 2,600 4,800 6,200 7,400 8,000 10,500 10,500 Further measuring ranges on request Thin-film sensor Process connection: 316L stainless steel, according to SEMI F20 (option: 316L VIM/VAR Thin-film sensor: 2.4711 / UNS R30003 304 SS 4 1 x 10° mbar I/sec (atm STD cc/sec) per SEMI F1 Electropolished, typical Ra ≤ 0.13 μm (RA 5); max. Ra ≤ 0.18 μm (RA 7) per SEMI F19 WU-20 < 1.5 cm², WU-25 < 1 cm², WU-26 < 1 cm²	Model WU-26 30

¹⁾ Including non-linearity, hysteresis, zero offset and end value deviation (corresponds to measured error per IEC 61298-2)

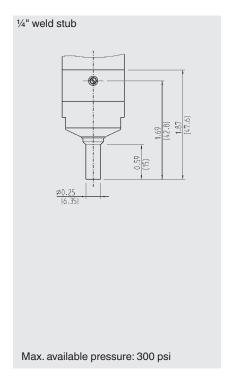


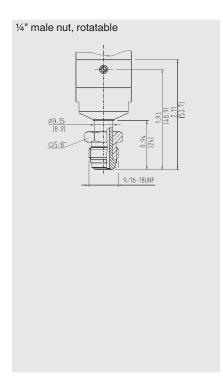


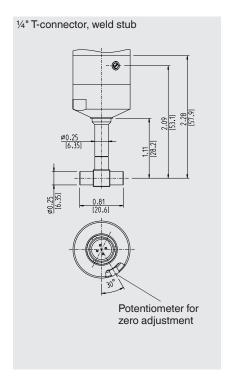
Dimensions in inch [mm], model WU-20



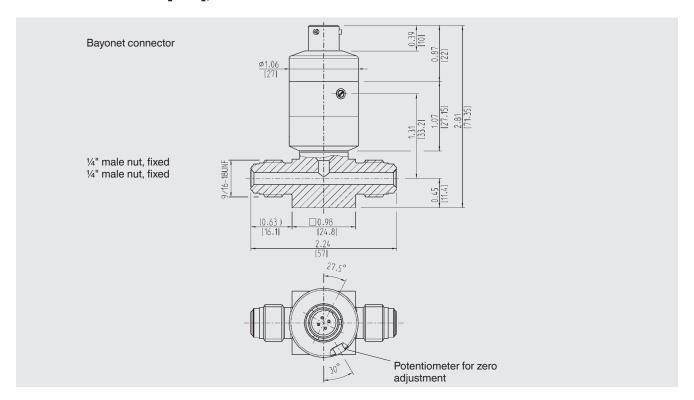
Process connections



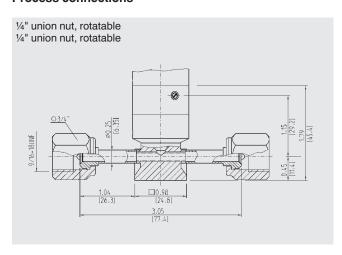


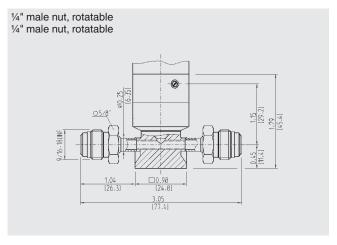


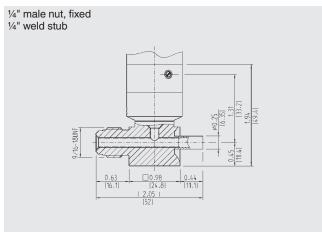
Dimensions in inch [mm], model WU-25

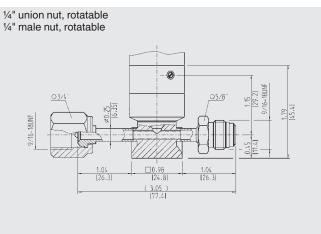


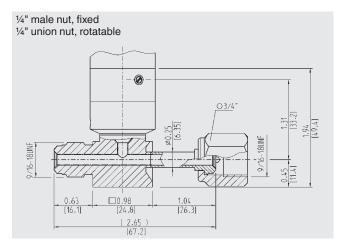
Process connections

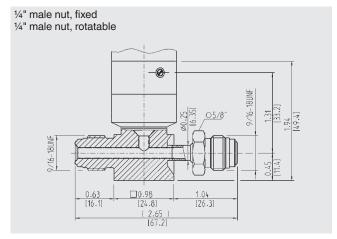


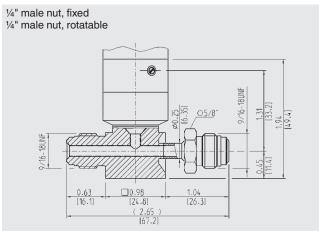


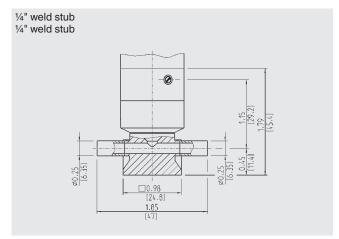






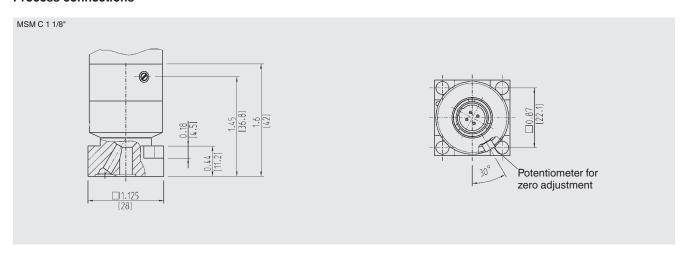






Dimensions in inch [mm], model WU-26

Process connections



Approvals

Logo	Description	Country
(€	EU declaration of conformity ■ EMC directive EN 61326 emission (group 1, class B) and interference immunity (industrial app Pressure equipment directive RoHS directive ATEX directive (option) Hazardous areas - Ex n Zone 2 gas [II 3G Ex nA ic IIC T6/T5/T4 Gc X]	
IEC IECEX	IECEx (option) Hazardous areas - Ex n Zone 2 gas [Ex nA ic IIC T6/T5/T4 Gc]	International
APPROVED	FM (option) Hazardous areas - Nonincendive Apparatus for use in Class I, Division 2, Groups A, B, C, D - Nonincendive for use in Class I, Zone 2, Group IIC (classified) locations	USA

Ordering information

Model / Measuring range / Process connection / Output signal / Power supply / Electrical connection / Cable length / Approval

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WIKA Alexander Wiegand SE & Co. KG

Alexander-Wiegand-Straße 30 63911 Klingenberg/Germany Tel. +49 9372 132-0 Fax +49 9372 132-406

info@wika.de www.wika.de